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Dated: May 14, 2002

Signature: 

(Marcys J. Millet)

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Docket No.: TESSERA 3.0-085 CONT DIV CIP
(PATENT)

#15/Lt to
Chapman

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Patent Application of:
Joseph Fjelstad

Application No.: 09/732,821

Group Art Unit: 2814

Filed: December 8, 2000

Examiner: A. Chambliss

For: METHODS FOR MANUFACTURING
RESISTORS USING A SACRIFICIAL
LAYER

Commissioner for Patents
Washington, DC 20231

COMMUNICATION

Dear Sir:

Subject to the approval of the Examiner handling this application, please replace sheets 4/17 and 16/17 of the drawings in this application with the attached sheets 4/17 and 16/17. As shown by the enclosed red-marked print, a figure number has been changed and two reference numerals have been deleted.

If there are any additional charges in connection with this requested amendment, the Examiner is authorized to charge applicant's Deposit Account No 12-1095 therefor.

Dated: May 14, 2002

Respectfully submitted,

By 

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